PATENT ASSIGNMENT

Electronic Version v1.1
Stylesheet Version v1.1

SUBMISSION TYPE:	CORRECTIVE ASSIGNMENT
NATURE OF CONVEYANCE:	Corrective Assignment to correct the name of the Inventor from Meng Fen Cai to Meng Feng Tsai previously recorded on Reel 024039 Frame 0886. Assignor(s) hereby confirms the name of the Inventor Meng Feng Tsai.

CONVEYING PARTY DATA

Name	Execution Date
Meng Feng Tsai	06/21/2011
Lily Jiang	12/18/2009
Jian Guang Chang	01/06/2010

RECEIVING PARTY DATA

Name:	Semiconductor Manufacturing International (Shanghai) Corporation
Street Address:	18 Zhang Jiang Road
Internal Address:	Pudong New Area
City:	Shanghai
State/Country:	CHINA
Postal Code:	201203

PROPERTY NUMBERS Total: 1

Property Type	Number
Application Number:	12647362

OP $40.00 12647362

CORRESPONDENCE DATA

Fax Number: (650)326-2422
Correspondence will be sent via US Mail when the fax attempt is unsuccessful.
Phone: 415-576-0200
Email: mtejera@kilpatricktownsend.com
Correspondent Name: KILPATRICK TOWNSEND AND STOCKTON LLP
Address Line 1: Two Embarcadero Center
Address Line 2: Eighth Floor
Address Line 4: San Francisco, CALIFORNIA 94111

ATTORNEY DOCKET NUMBER:	87720-722356 (015710US)
NAME OF SUBMITTER:	Dah Bin Kao

Total Attachments: 13
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Attorney Docket No.: 87720-722356
(IP Family 015710US)
Client Reference No. 2004-00267-SH-US-DA1

ASSIGNMENT OF PATENT APPLICATION

JOINT

WHEREAS, Lily Jiang of 18 Zhang Jiang Rd., Pudong New Area, Shanghai 201203; People's Republic of China, Meng Fen Cai of 18 Zhang Jiang Rd., Pudong New Area, Shanghai 201203; People's Republic of China and Jian Guang Chang of 18 Zhang Jiang Rd., Pudong New Area, Shanghai 201203, People's Republic of China, hereinafter referred to as "Assignors," are the inventors of the invention described and set forth in the below-identified application for United States Letters Patent:

Title of Invention:	A Method and Structure for Performing a Chemical Mechanical Polishing Process
Filing Date:	December 29, 2009
Application No.:	12/647,362 ; and

WHEREAS, Semiconductor Manufacturing International (Shanghai) Corporation, a corporation of People's Republic of China, located at 18 Zhang Jiang Rd, Pudong New Area, Shanghai, 201203 People's Republic of China, hereinafter referred to as "ASSIGNEE," is desirous of acquiring an interest in the invention and application and in any U.S. Letters Patent and Registrations which may be granted on the same;

For good and valuable consideration, receipt of which is hereby acknowledged by Assignors, Assignors have assigned, and by these presents do assign to Assignee all right, title and interest in and to the invention and application and to all foreign counterparts (including patent, utility model and industrial designs), and in and to any Letters Patent and Registrations which may hereafter be granted on the same in the United States and all countries throughout the world, and to claim the priority from the application as provided by the Paris Convention. The right, title and interest is to be held and enjoyed by Assignee and Assignee's successors and assigns as fully and exclusively as it would have been held and enjoyed by Assignors had this Assignment not been made, for the full term of any Letters Patent and Registrations which may be granted thereon, or of any division, renewal, continuation in whole or in part, substitution, conversion, reissue, prolongation or extension thereof.

Assignors further agree that they will, without charge to Assignee, but at Assignee's expense, (a) cooperate with Assignee in the prosecution of U.S. Patent applications and foreign counterparts on the invention and any improvements, (b) execute, verify, acknowledge and deliver all such further papers, including patent applications and instruments of transfer, and (c) perform such other acts as Assignee lawfully may request to obtain or maintain Letters Patent and Registrations for the invention and improvements in any and all countries, and to vest title thereto in Assignee, or Assignee's successors and assigns.

Assignors hereby authorize and request Townsend and Townsend and Crew LLP, Two Embarcadero Center, Eighth Floor, San Francisco, CA 94111-3834, to insert herein above the application number and filing date of said application when known.

IN TESTIMONY WHEREOF, Assignors have signed their names on the dates indicated.

Dated: ____________________ ____________________
Lily Jiang

Dated: 2011-6-21 Meng Feng Tsai
Meng Feng Tsai

Dated: ______________________

____
Jian Guang Chang

PATENT ASSIGNMENT

Electronic Version v1.1
Stylesheet Version v1.1

03/07/2010
501111578

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT

CONVEYING PARTY DATA

Name	Execution Date
LILY JIANG	12/18/2009
MENG FEN CAI	01/07/2010
JIAN GUANG CHANG	01/06/2010

RECEIVING PARTY DATA

Name:	Semiconductor Manufacturing International (Shanghai) Corporation
Street Address:	18 Zhang Jiang Road, Pudong New Area
City:	Shanghai
State/Country:	CHINA
Postal Code:	201203

PROPERTY NUMBERS Total: 1

Property Type	Number
Application Number:	12647362

CH $40.00 12647362

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Phone:	650-326-2400
Email:	jbsalvador@townsend.com
Correspondent Name:	TOWNSEND AND TOWNSEND AND CREW LLP
Address Line 1:	Two Embarcadero Center, Eighth Floor
Address Line 4:	San Francisco, CALIFORNIA 94111-3834

ATTORNEY DOCKET NUMBER:	021653-015710US
NAME OF SUBMITTER:	Ardeshir Tabibi

Total Attachments: 2
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Attorney Docket No.: 021653-015710US
Client Reference No. 2004-00267-SH-US-DA1

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Title of Invention:	A Method and Structure for Performing a Chemical Mechanical Polishing Process
Filing Date:	Not Yet Filed
Application No.:	Not Yet Assigned ; and

WHEREAS, Semiconductor Manufacturing International (Shanghai) Corporation, a corporation of People's Republic of China, located at 18 Zhang Jiang Rd, Pudong New Area, Shanghai, 201203 People's Republic of China, hereinafter referred to as "ASSIGNEE," is desirous of acquiring an interest in the invention and application and in any U.S. Letters Patent and Registrations which may be granted on the same;

For good and valuable consideration, receipt of which is hereby acknowledged by Assignors, Assignors have assigned, and by these presents do assign to Assignee all right, title and interest in and to the invention and application and to all foreign counterparts (including patent, utility model and industrial designs), and in and to any Letters Patent and Registrations which may hereafter be granted on the same in the United States and all countries throughout the world, and to claim the priority from the application as provided by the Paris Convention. The right, title and interest is to be held and enjoyed by Assignee and Assignee's successors and assigns as fully and exclusively as it would have been held and enjoyed by Assignors had this Assignment not been made, for the full term of any Letters Patent and Registrations which may be granted thereon, or of any division, renewal, continuation in whole or in part, substitution, conversion, reissue, prolongation or extension thereof.

Assignors further agree that they will, without charge to Assignee, but at Assignee's expense, (a) cooperate with Assignee in the prosecution of U.S. Patent applications and foreign counterparts on the invention and any improvements, (b) execute, verify, acknowledge and deliver all such further papers, including patent applications and instruments of transfer, and (c) perform such other acts as Assignee lawfully may request to obtain or maintain Letters Patent and Registrations for the invention and improvements in any and all countries, and to vest title thereto in Assignee, or Assignee's successors and assigns.

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IN TESTIMONY WHEREOF, Assignors have signed their names on the dates indicated.

Dated: 2009/12/18

Lily_Jiang 蒋莉
Lily Jiang

Dated: 2010-1-7

Mengfen Tsai
Meng Fen Cai

Dated: 2010. 01. 06

Jian Guang Chang

Attorney Docket No.: 021653-015710US
Client Reference No. 2004-00267-SH-US-DA1

ASSIGNMENT OF PATENT APPLICATION

JOINT

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Dated: 2009/12/18 Lily Jiang

Lily Jiang

Dated: 2010-1-7 Meng Fen Tsai

Meng Fen Cai

Dated: 2010. 01. 06

Jian Guang Chang

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